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**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Tatsuo ITO et al.

Application No.: 10/502,389

Docket No.: 120503

Filed: July 26, 2004

For: METHOD FOR MANUFACTURING SEMICONDUCTOR WAFER, METHOD  
FOR RECEIVING ORDER FOR MANUFACTURE OF SEMICONDUCTOR  
WAFER, AND SYSTEM FOR RECEIVING ORDER FOR MANUFACTURE OF  
SEMICONDUCTOR WAFER

**REQUEST FOR CORRECTION OF PALM RECORDS**

Commissioner for Patents  
P.O. Box 1450  
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Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

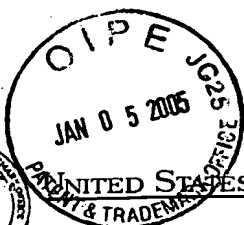
Eric D. Morehouse  
Registration No. 38,565

JAO:EDM/cqc

Date: January 5, 2005

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 19928**  
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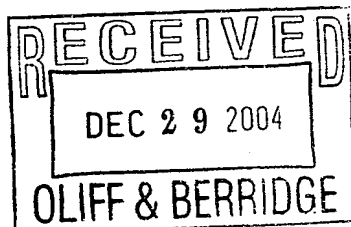


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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/502,389	07/26/2004	2812	1190	120503	6	35	3

25944  
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CONFIRMATION NO. 3456

## FILING RECEIPT



\*OC000000014830077\*

Date Mailed: 12/28/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. **If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).**

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## Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP03/00557 01/22/2003

## Foreign Applications

JAPAN 200219334 01/29/2002

Projected Publication Date: 04/07/2005

Non-Publication Request: No

Early Publication Request: No

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Title

~~Semiconductor wafer manufacturing method, semiconductor wafer manufacturing order acceptance method, and semiconductor wafer manufacturing order acceptance system~~

Preliminary Class  
438

Method for Manufacturing Semiconductor Wafer, Method  
for Receiving Order for Manufacture of Semiconductor  
Wafer, and System for Receiving Order for Manufacture of  
Semiconductor Wafer

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